

**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Mikihiko ISHII et al.

Application No.: New U.S. Continuing Application

Filed: March 18, 2004

Docket No.: 119132

For: METHOD AND APPARATUS FOR POINT DIFFRACTION INTERFEROMETRY

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Please consider the following:

**Amendments to the Specification;**

**Remarks.**